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PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Shinichi FUKADA

Group Art Unit: 2811

Application No.: 10/849,016

Examiner: S. Gebremariam

Filed: May 20, 2004

Docket No.: 119798

For: SEMICONDUCTOR DEVICE AND METHOD FOR MANUFACTURING THE SAME

RESPONSE TO RESTRICTION REQUIREMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

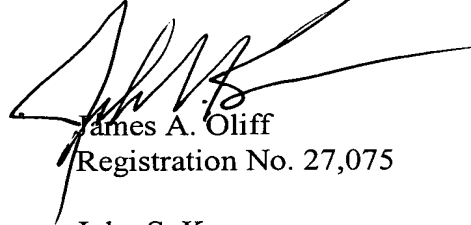
Sir:

In reply to the February 9, 2005 Restriction Requirement, Applicant provisionally elects Group I, claims 1-7, drawn to a method of forming integrated circuit device, classified in class 438, subclass 100+, with traverse.

It is also respectfully submitted that the subject matter of all claims 1-10 is sufficiently related that a thorough search for the subject matter of any one Group of claims would encompass a search for the subject matter of the remaining claims. Thus, it is respectfully submitted that the search and examination of the entire application could be made without serious burden. See MPEP §803 in which it is stated that "if the search and examination of an entire application can be made without serious burden, the examiner must examine it on the merits, even though it includes claims to independent or distinct inventions" (emphasis added). It is respectfully submitted that this policy should apply in the present application in order to avoid unnecessary delay and expense to Applicant and duplicative examination by the Patent Office.

Thus, withdrawal of the Restriction Requirement is respectfully requested.

Respectfully submitted,



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Date: March 8, 2005

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